

# Integrated Sensor System for Signal Conditioning, Digitization and Interfacing for Terahertz Bolometric Camera

SENSORDEVICES 2019

27 – 31 October 2019, Nice, France

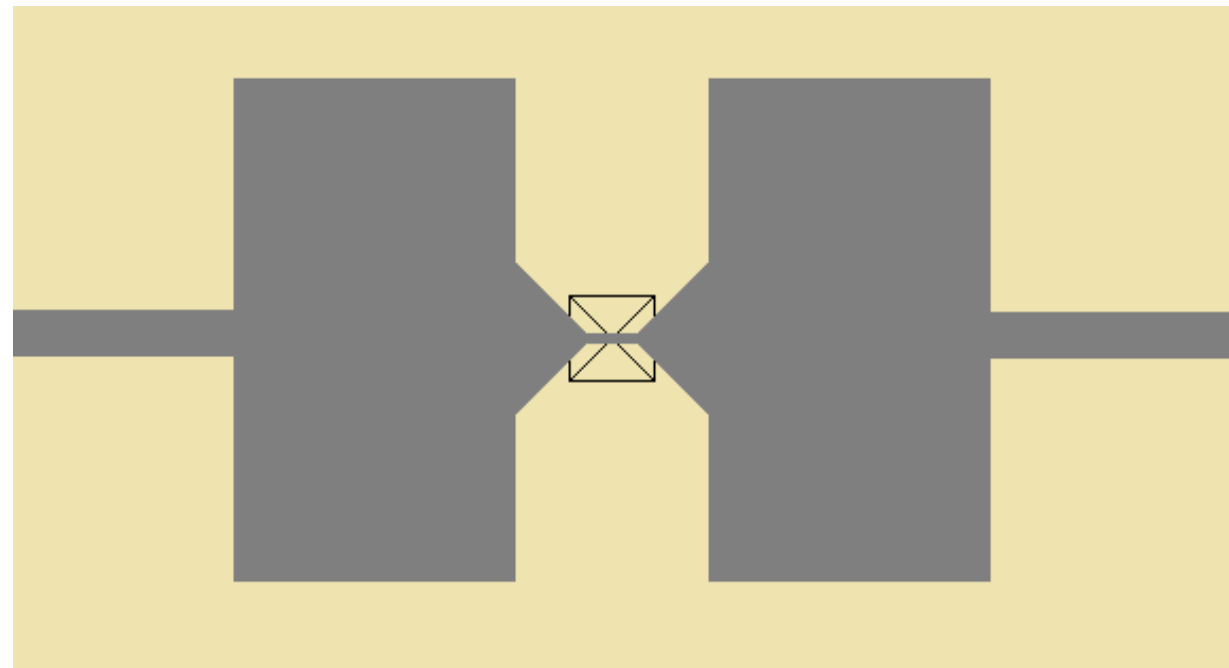
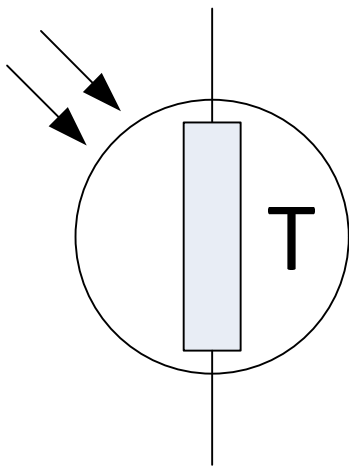
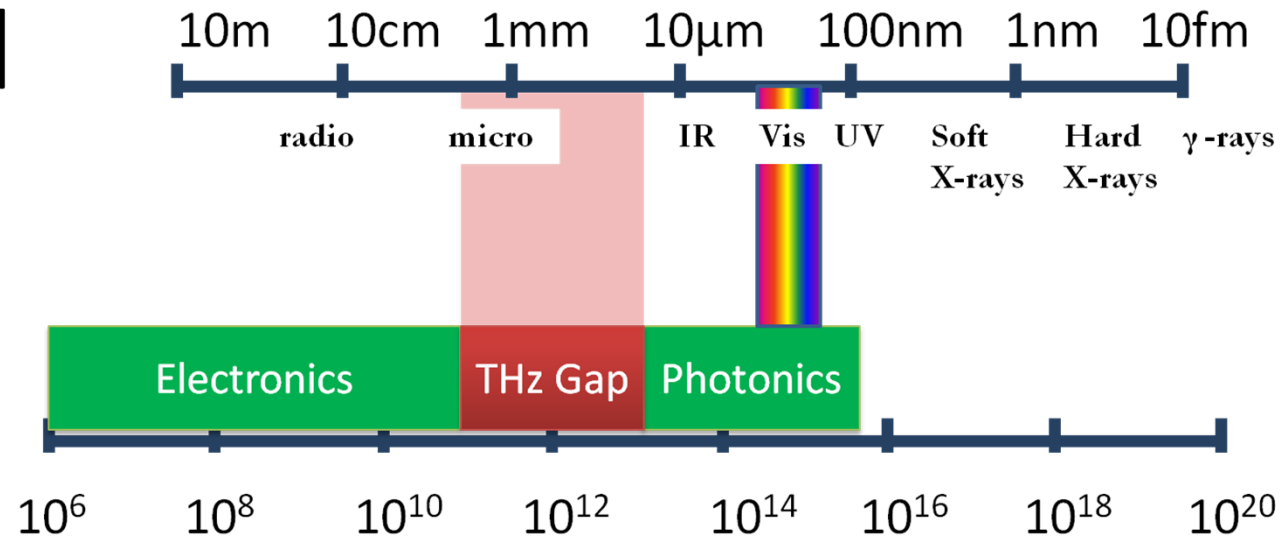
Tomo Markočič, prof. dr. Janez Trontelj

University of Ljubljana, Faculty of Electrical Engineering  
Laboratory for Microelectronics

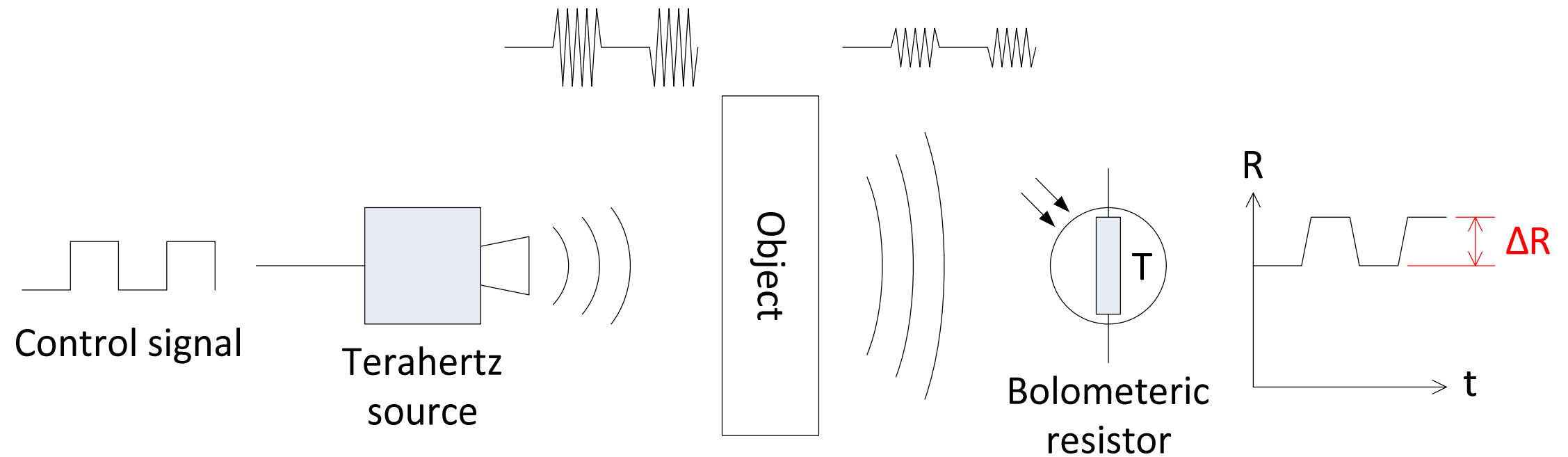
# Agenda

- Introduction to THz and bolometers
- Idea
  - Existing system
  - Novel system
- Analogue processing
- Low-noise amplifier design
  - Lateral Bipolar Transistor Structure
- Conclusion

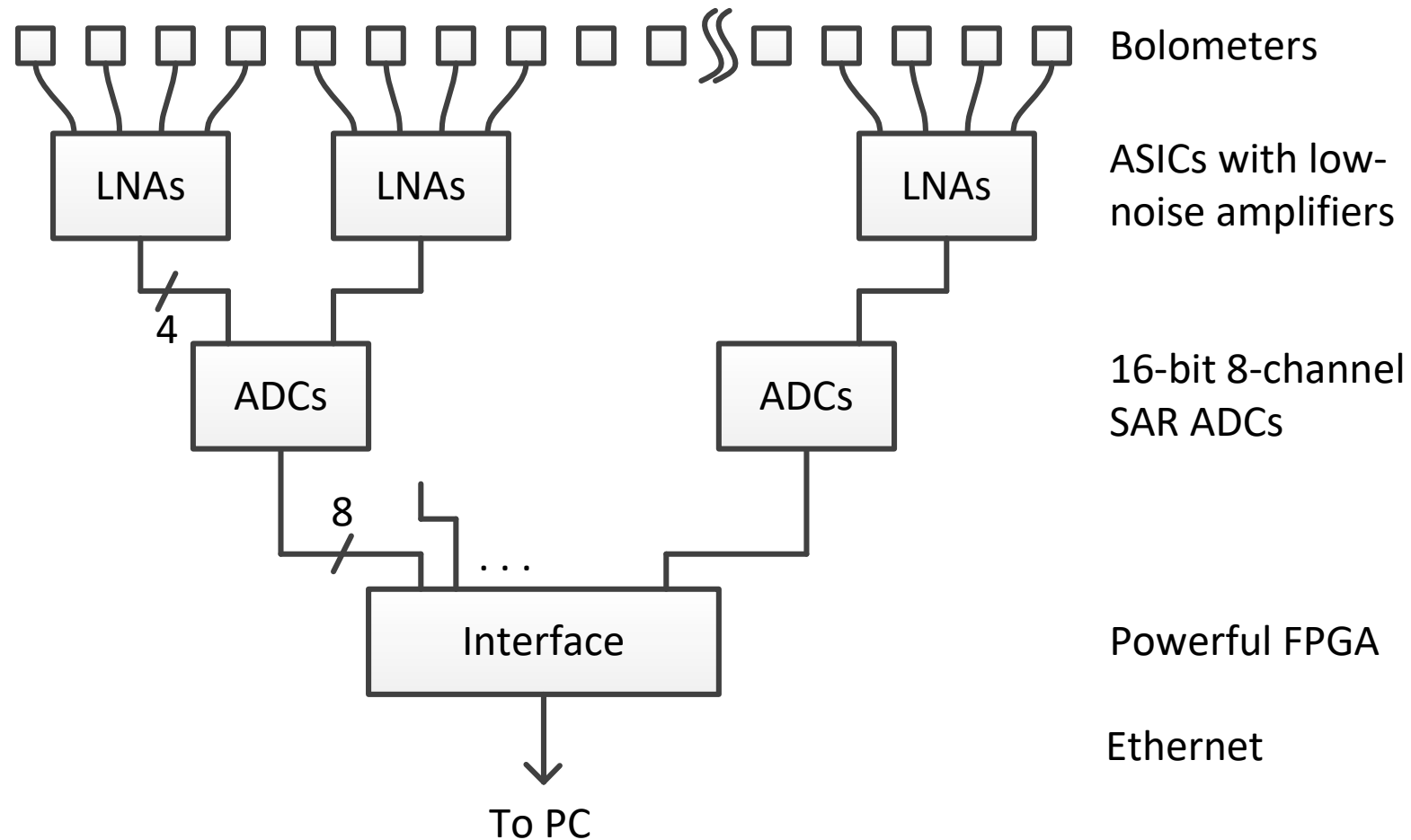
# THz waves and Bolometers



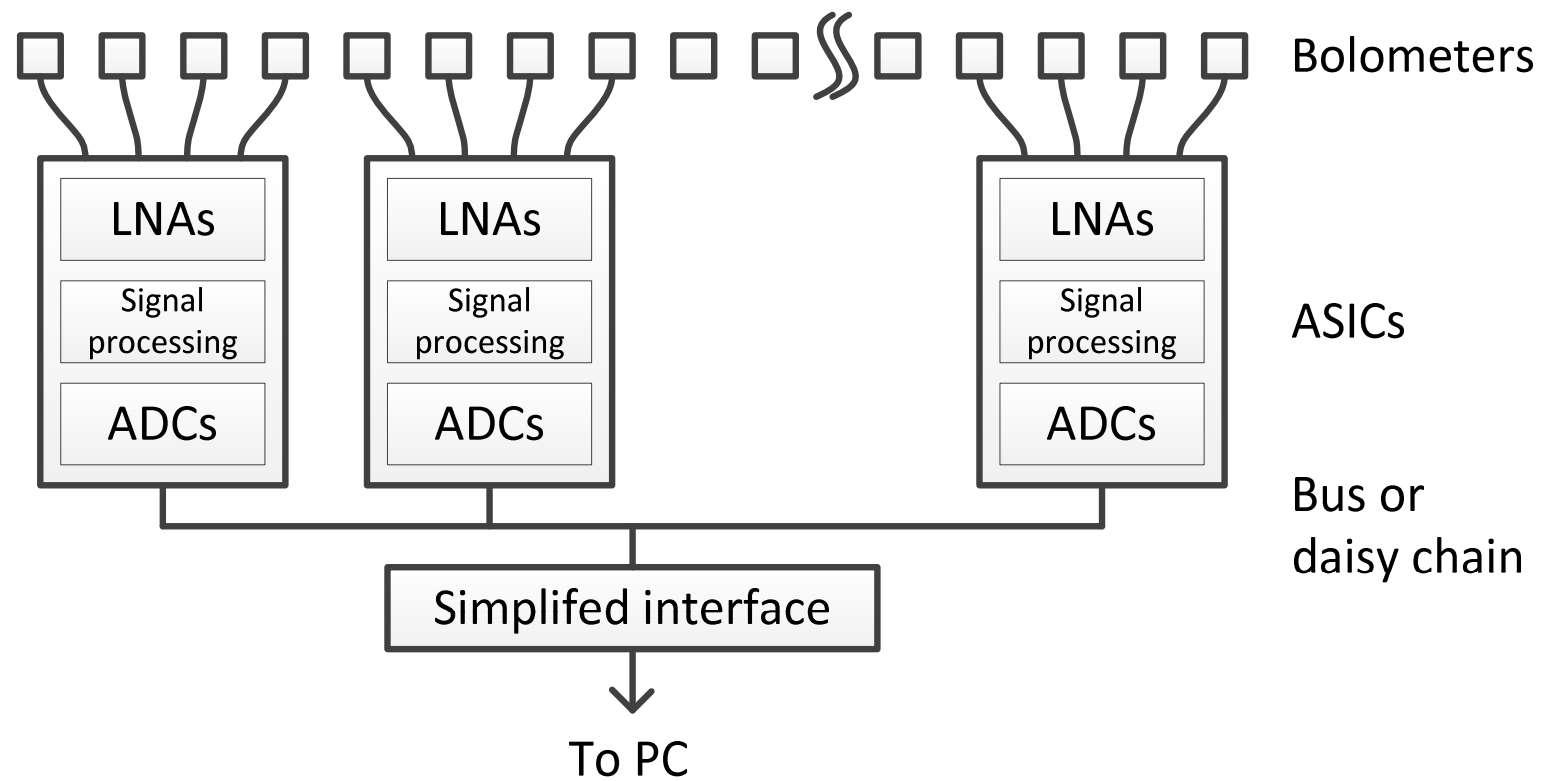
# THz waves and Bolometers



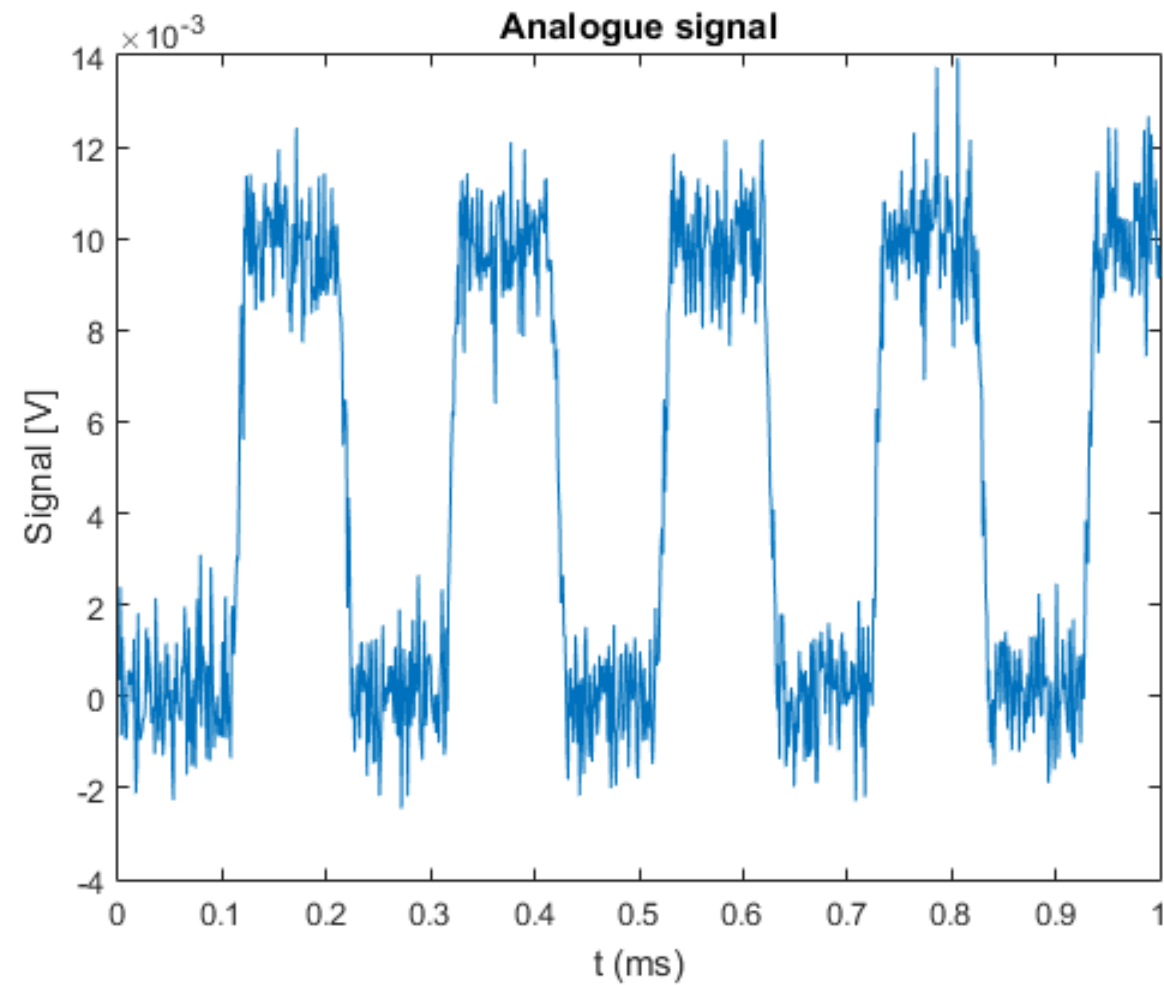
# Existing THz camera system



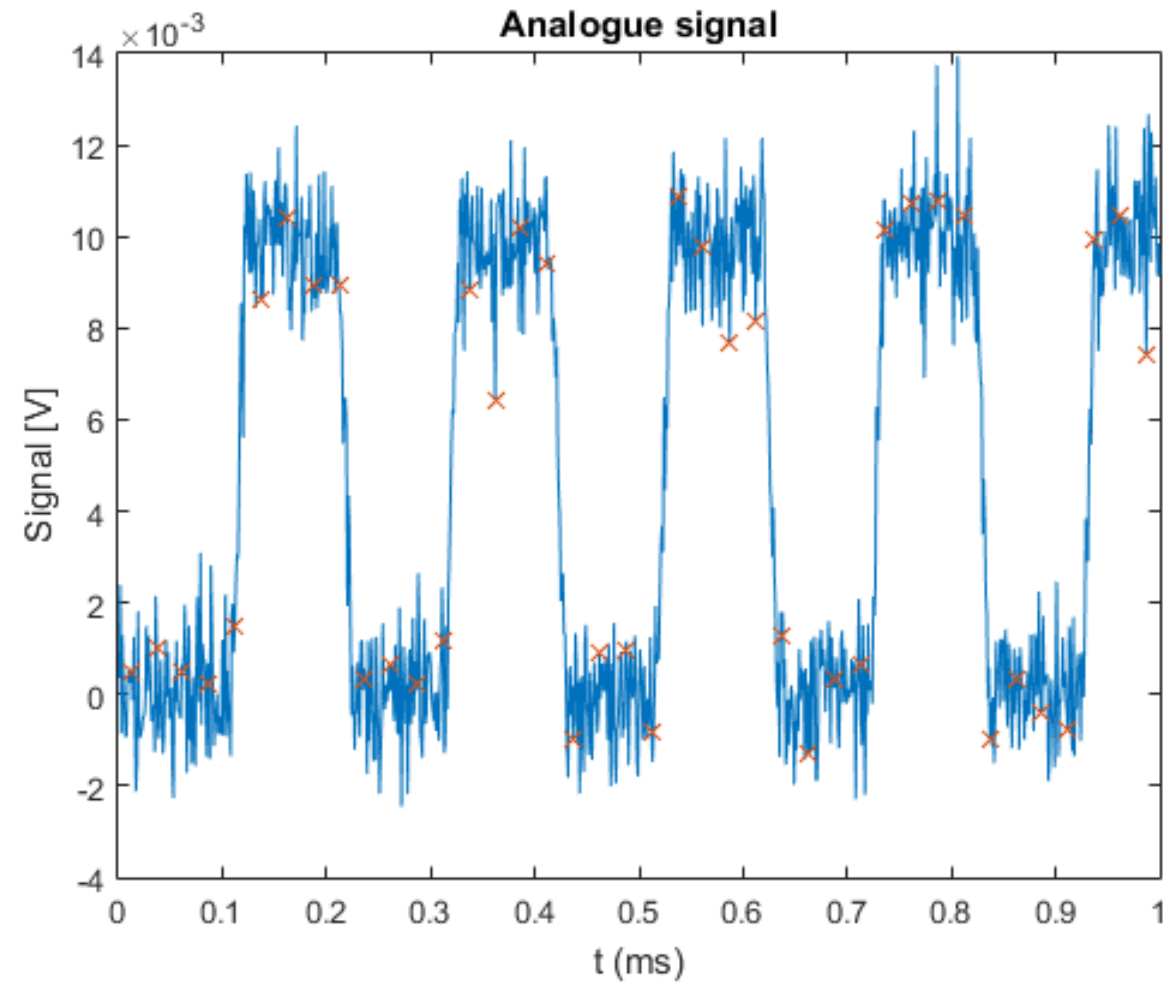
# Novel system



# Noise rejection

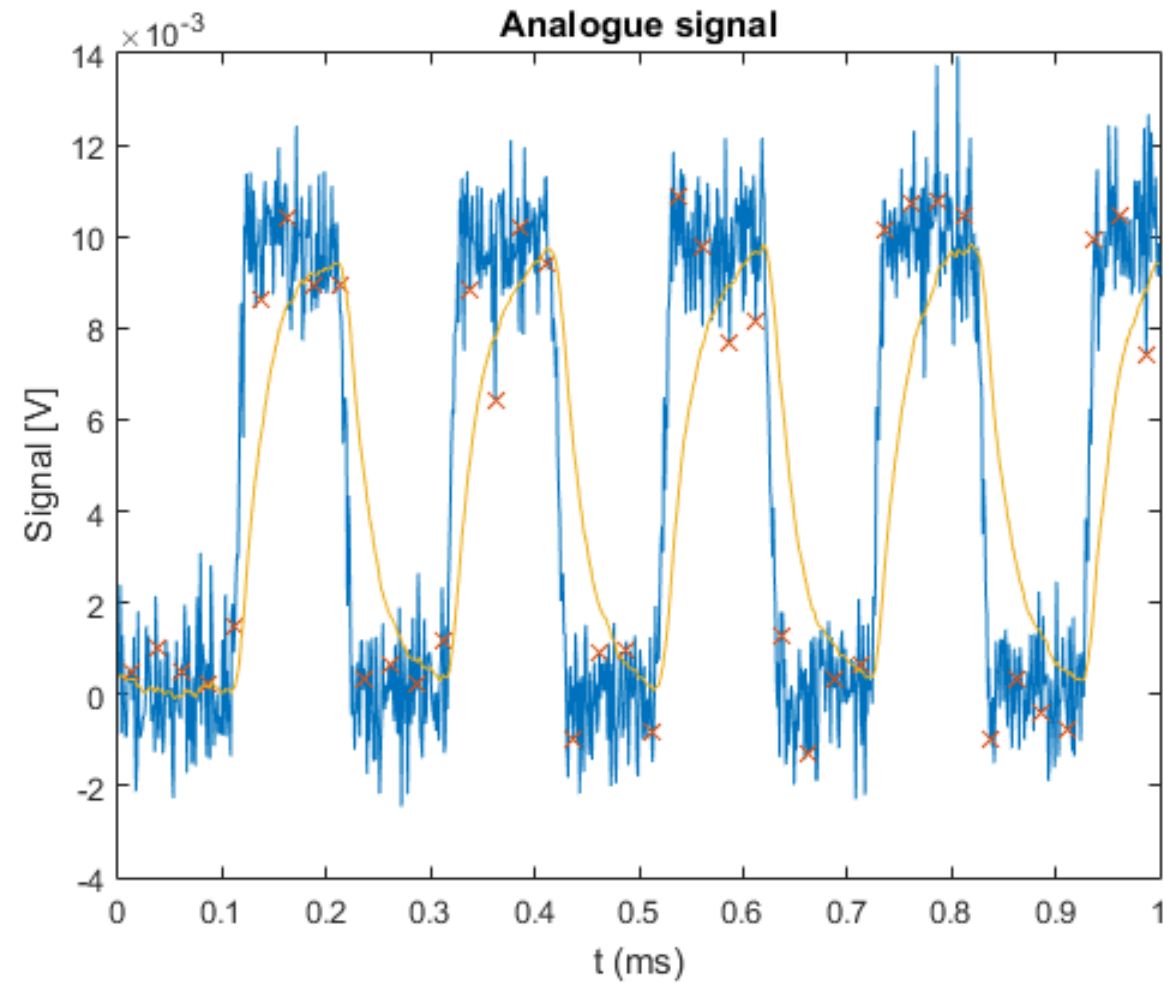


# Noise rejection

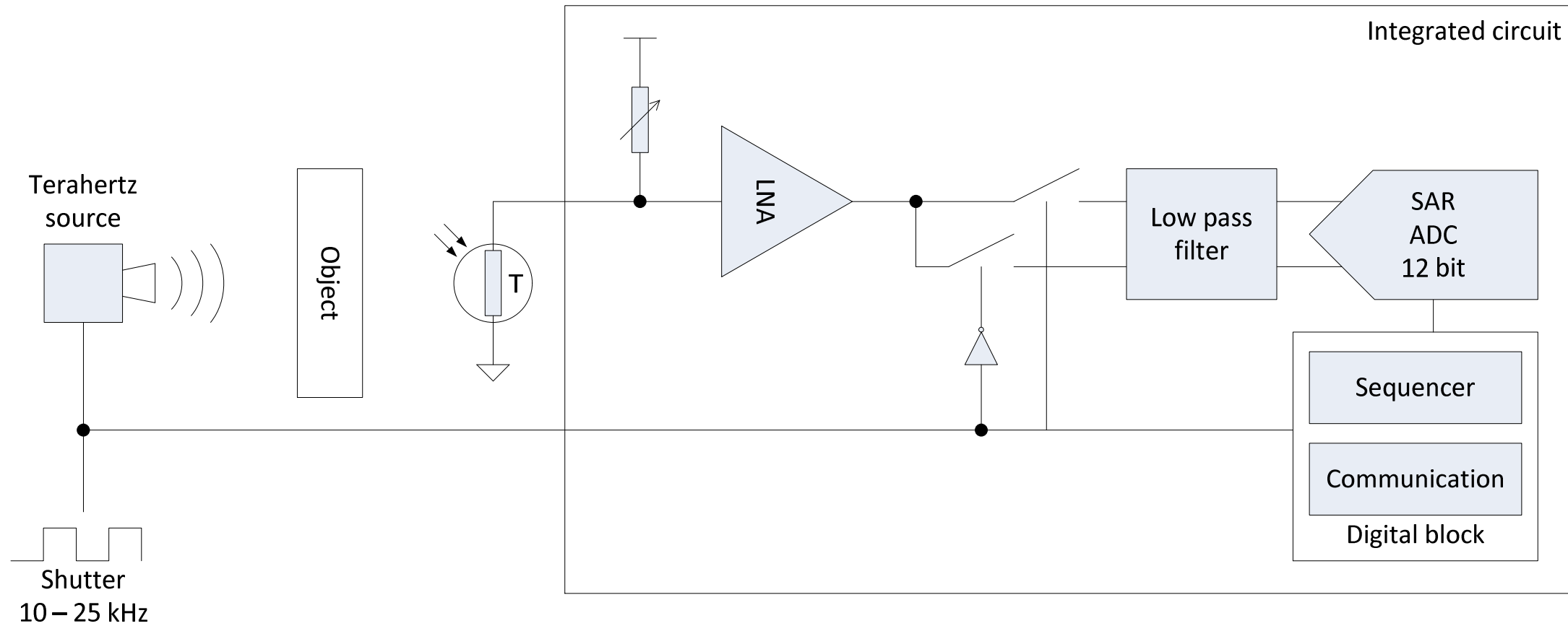
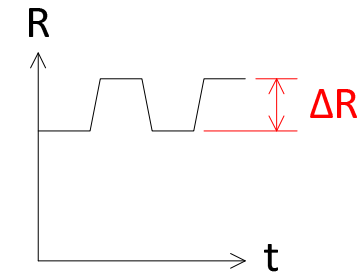




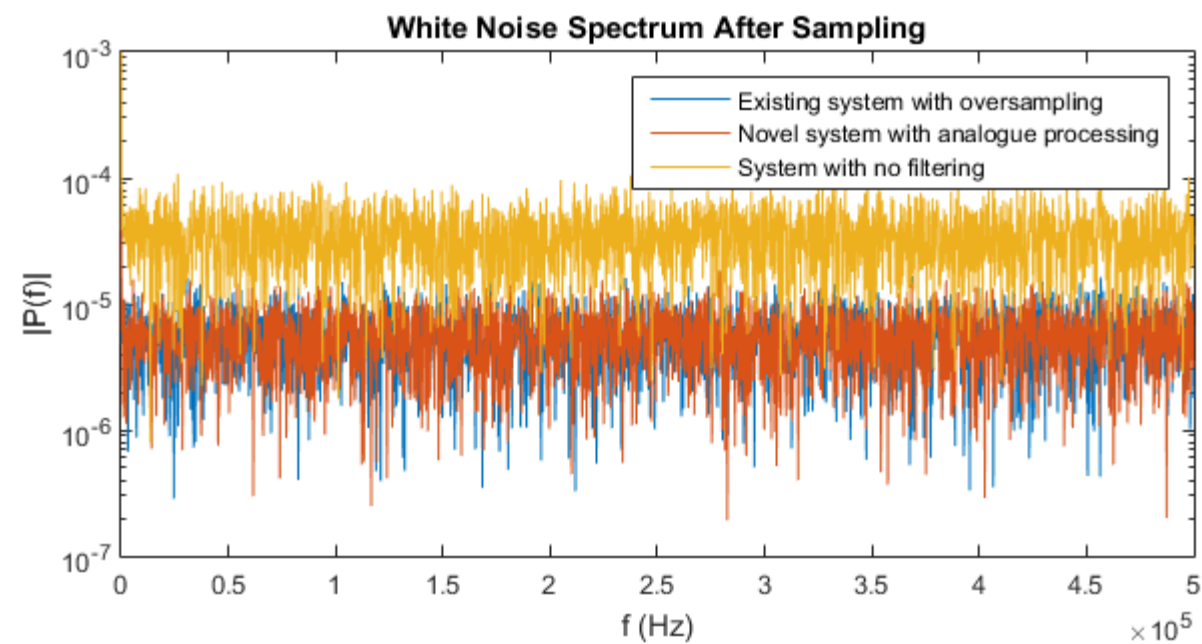
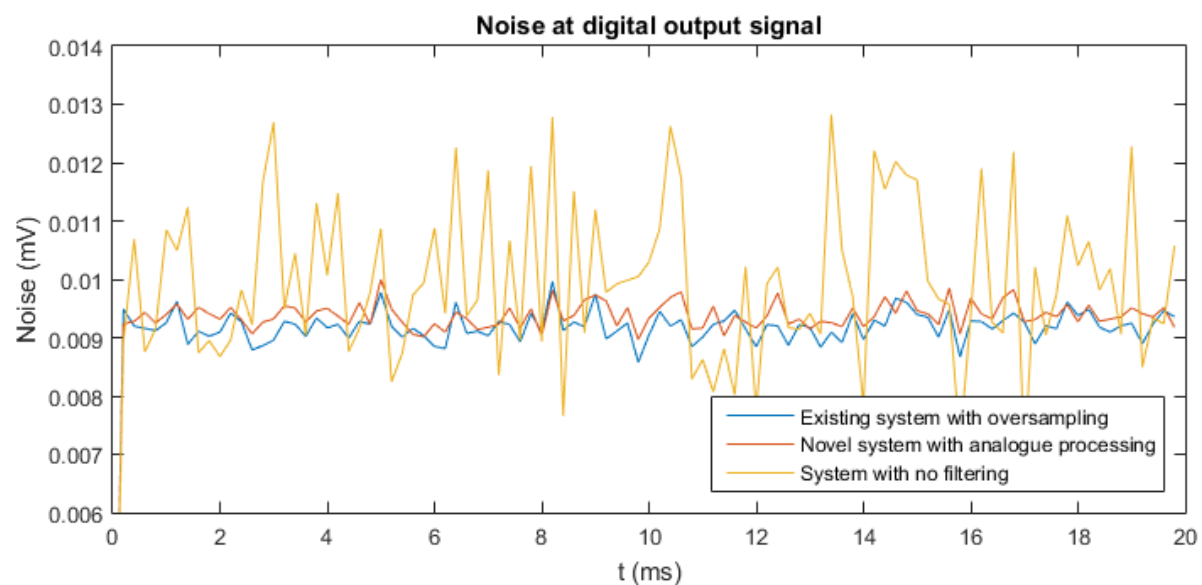
# Noise rejection



# The integrated circuit



# Noise rejection

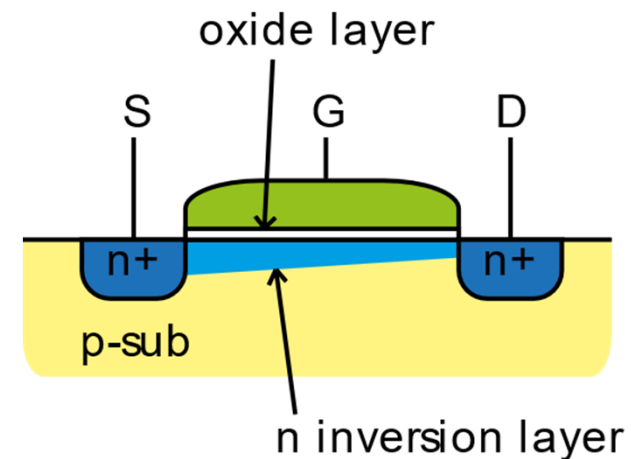


# Amplifier

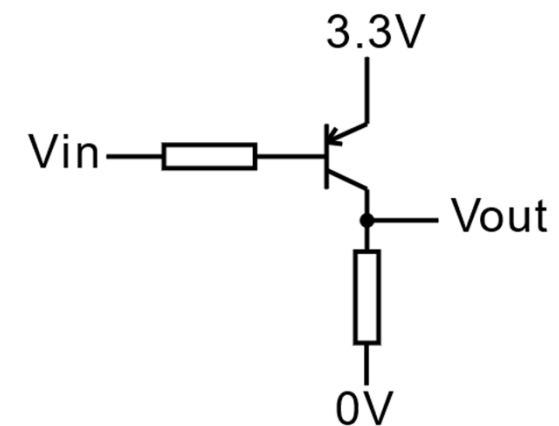
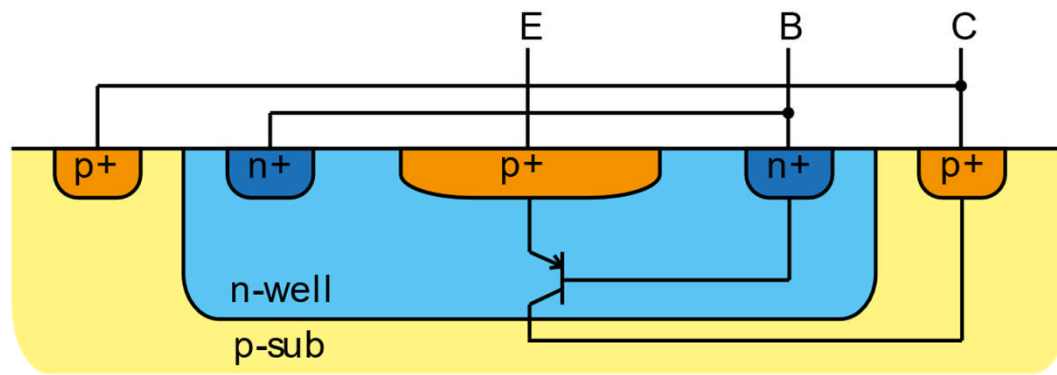
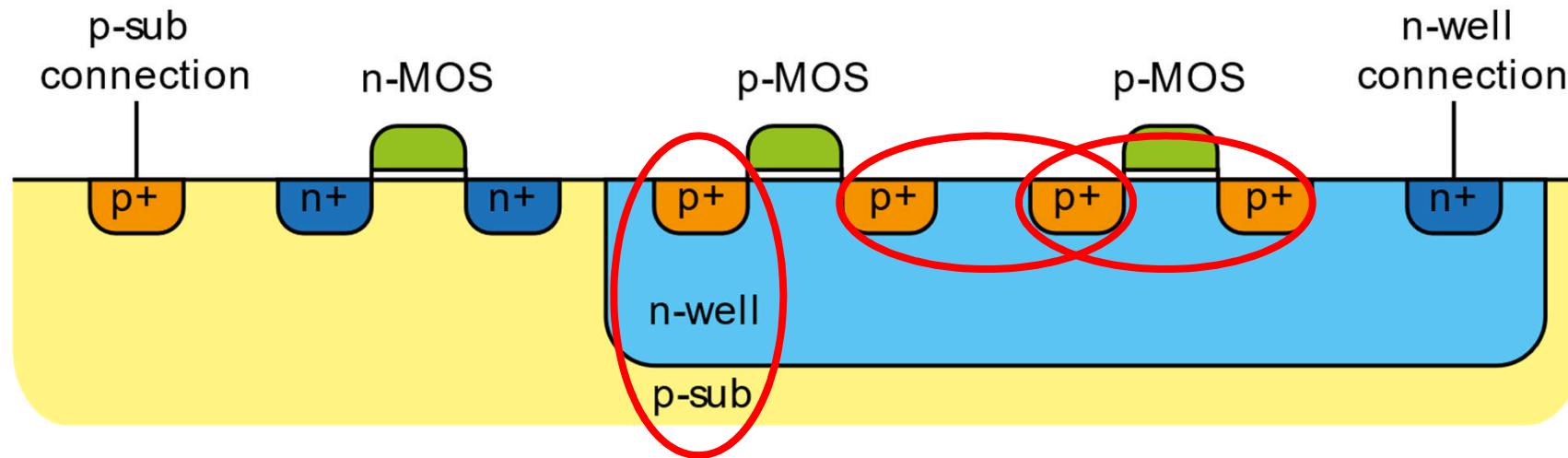
- Low noise amplifier (LNA) design
- Existing amplifier in Complementary metal-oxide-semiconductor (CMOS) technology
  - 5nV/ $\sqrt{\text{Hz}}$  noise at 1kHz
  - 60dB closed loop gain
  - $\sim 900\mu\text{A}$  current consumption
  - $\sim 0.5\text{mm}^2$  area
- Requirement for new amplifier
  - 2nV/ $\sqrt{\text{Hz}}$
  - Same gain
  - Power consumption not increased
  - Area not increased
  - Same technology (CMOS 0.35 $\mu\text{m}$ )

# CMOS to BJT noise comparison

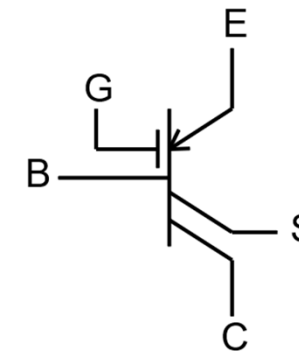
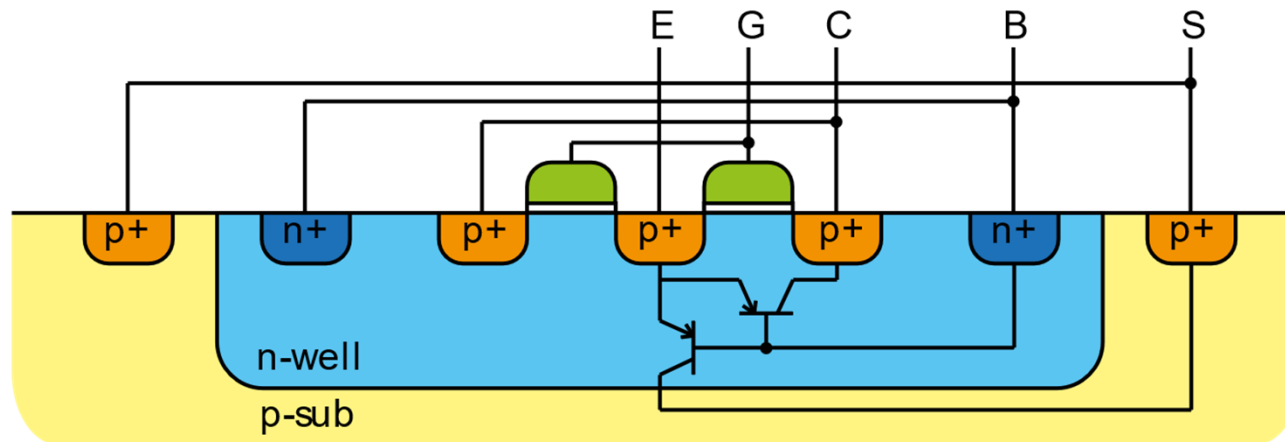
- (C)MOS Transistor
  - Charge carriers trapped in oxide layer
  - Scattering in inversion layer
  - 1/f dominant noise
- BJT (Bipolar Junction Transistor)
  - No inversion layer
  - White noise inversely proportional to collector current



# Layers in TSMC 0.35 $\mu\text{m}$ CMOS

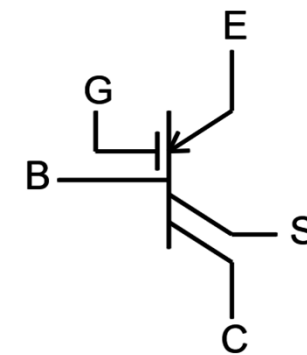
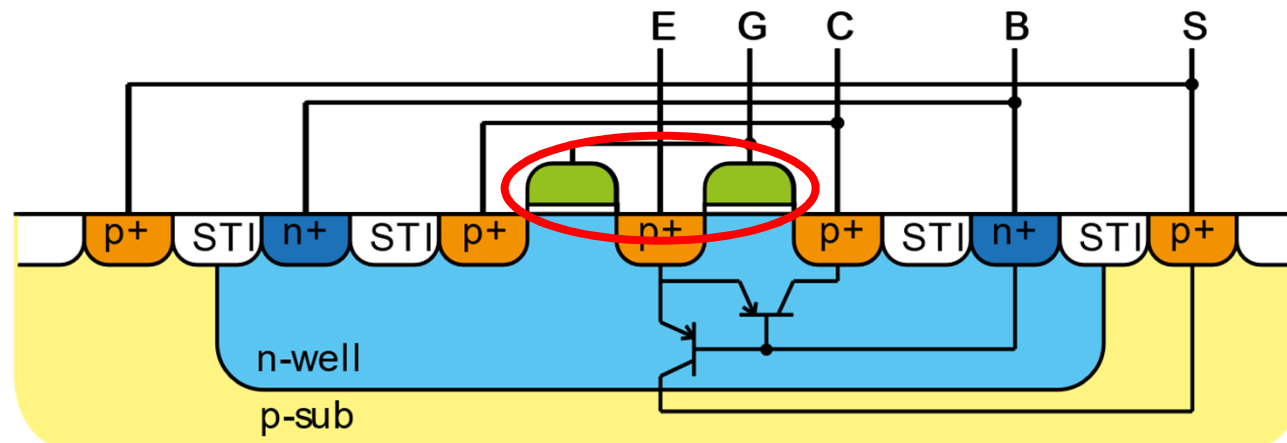


# Lateral bipolar transistor structure



# Purpose of the gate

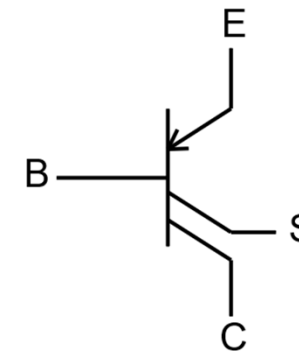
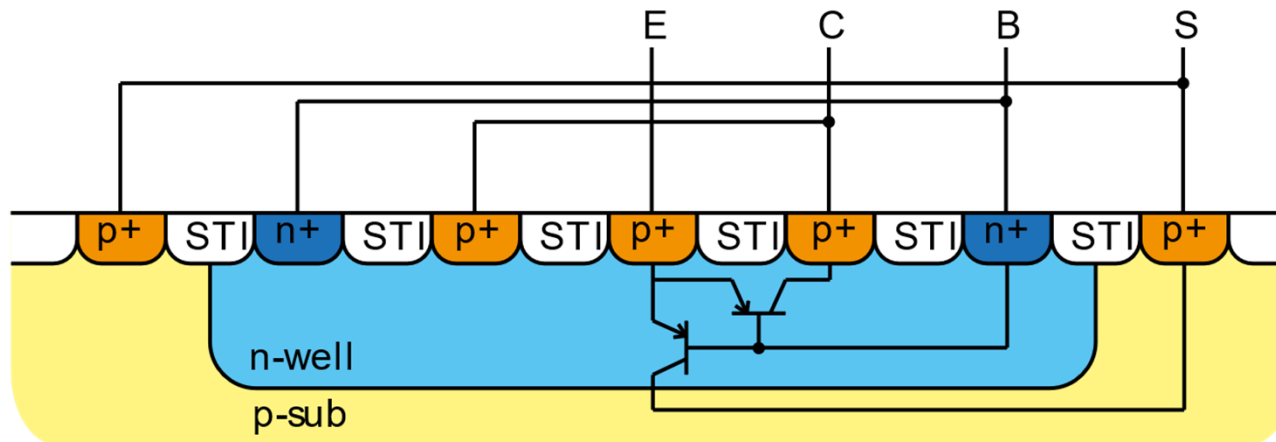
- Shallow trench isolation (STI)





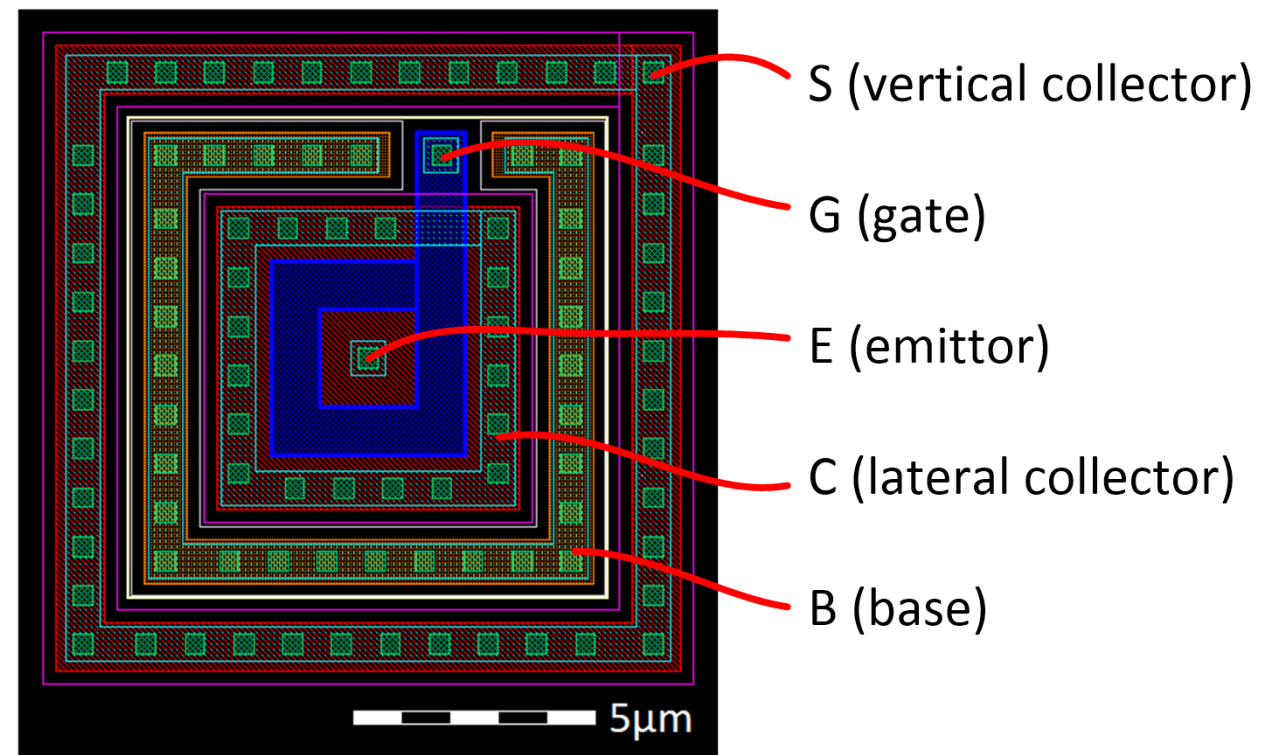
# Purpose of the gate

- Shallow trench isolation (STI)



# Test structures

- Initial design taken from a similar CMOS technology of a different fab
- Emitter size  $2\mu\text{m} \times 2\mu\text{m}$
- Device size  $13\mu\text{m} \times 13\mu\text{m}$  (array pitch  $11.5\mu\text{m}$ )
- Test structure is an array of 200 devices
- Two structures with different gate length

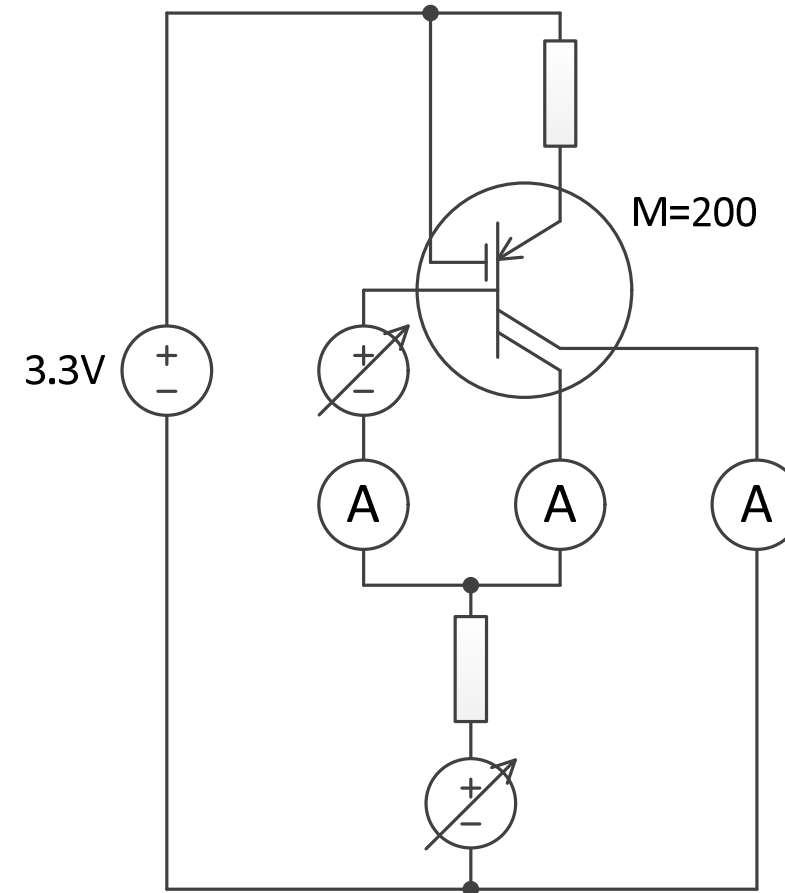


# Test structures measurement

- Aim to determine  $\beta$  factors for both, lateral and vertical collector

$$\beta = I_C / I_B$$

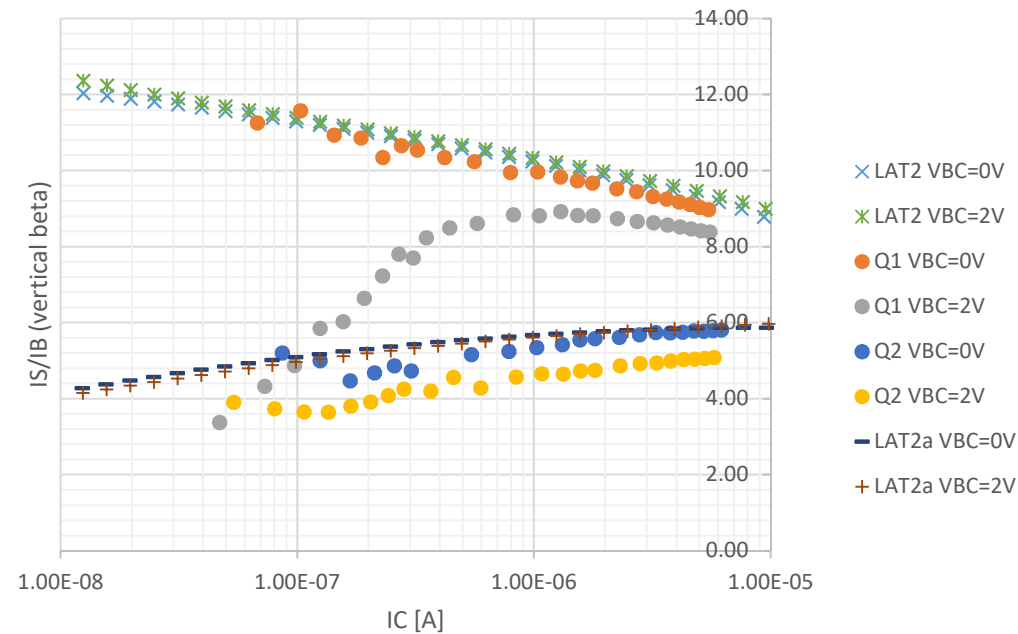
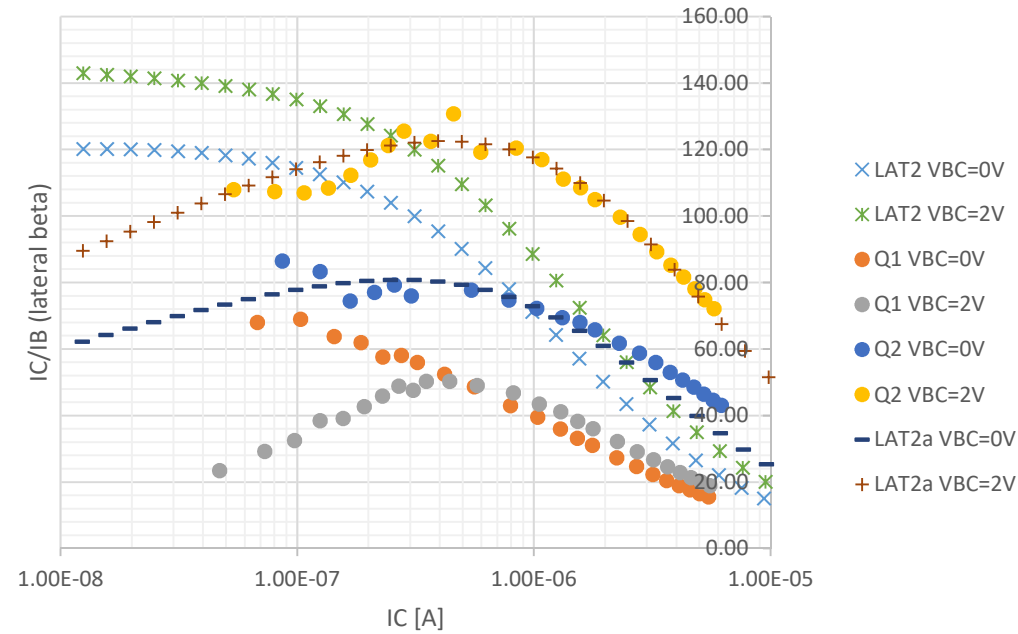
- Sweep collector current for different  $V_{BC}$  conditions



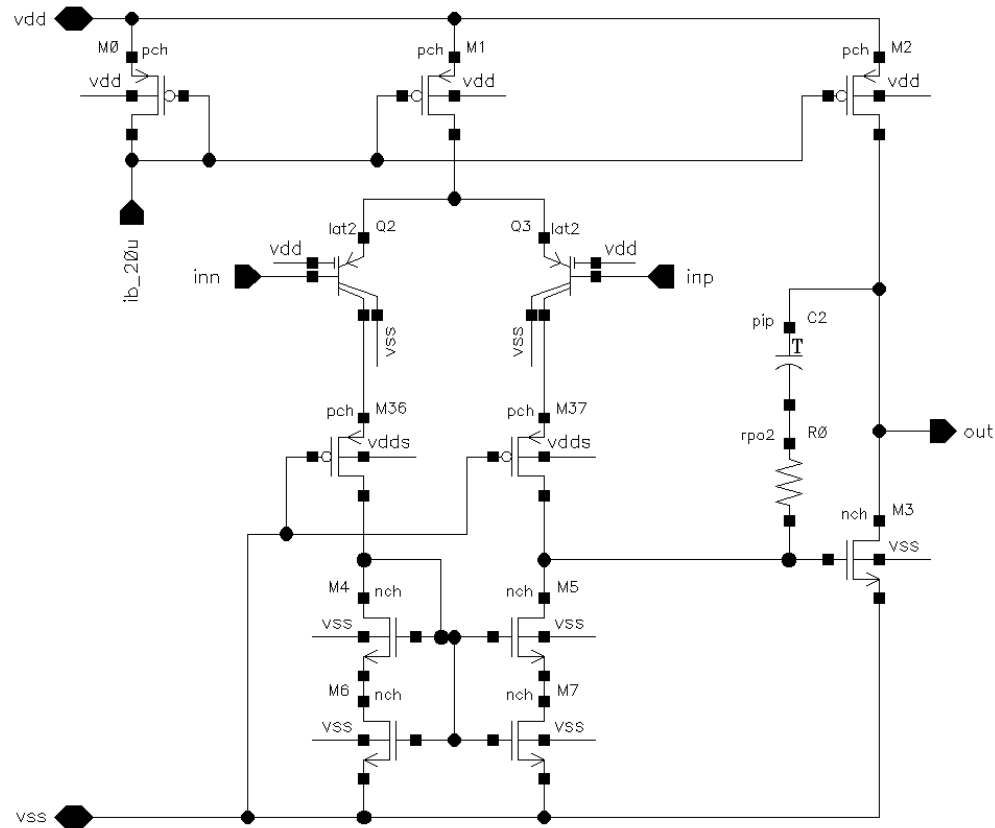
# Results

In comparison to LAT2 model

- Q1
  - Smaller  $\beta_{LAT}$
  - Unaffected by  $V_{BC}$
- Q2
  - Better  $\beta_{LAT}$  at higher currents
  - Smaller  $\beta_{VERT}$



# Amplifier design



Simulation results		
	Existing CMOS LNA	This work
I supply	948.5 $\mu$ A	499.9 $\mu$ A
Input noise at 100 Hz	12.86 nV/ $\sqrt$ Hz	5.062 nV/ $\sqrt$ Hz
Input noise at 1 kHz	4.99 nV/ $\sqrt$ Hz	2.637 nV/ $\sqrt$ Hz
Silicon area	0.516 mm <sup>2</sup>	0.22 mm <sup>2</sup>

Yet to be tested!

# Conclusion

- Demonstrated feasibility of novel system
  - Analogue processing shows promising results
  - Reduced hardware cost
- New low-noise amplifier
  - Use of custom structures
  - Promising simulation results
- More work to be done

Thank you for your attention